

This listing of claims will replace all prior versions, and listings, of claims in the application

LISTING OF CLAIMS

- 1-8. (canceled).
9. (new) An image detector for an x-ray image, comprising:
a luminophore layer;
a protective layer lying over the luminophore layer, the protective layer being hardened only in a region not abutting the luminophore layer.
10. (new) The image detector according to claim 9, further comprising a non-hardened region that abuts the luminophore layer that is at least 5 μm thick.
11. (new) The image detector according to claim 9, wherein the hardened region that does not abut the luminophore layer is at least 3 μm thick.
12. (new) The image detector according to claim 9, wherein the hardened region of the protective layer is an electron-beam-treatment hardened region.
13. (new) The image detector according to claim 9, wherein the protective layer is comprised of poly-para-xylylene.
14. (new) The image detector according to claim 9, wherein the luminophore layer is a needle image plate.

15. (new) The image detector according to claim 9, wherein the luminophore layer is comprised of alkali halogenides or alkaline earth halogenides.
16. (new) The image detector according to claim 15, wherein the luminophore layer is comprised of CsBr:Eu, BaFBr:Eu, RbBr:Tl, CsBr:Ga, CsI:Na or CsI:Tl.
17. (new) A method for producing a polymer protective layer on an image detector for an x-ray image that comprises a luminophore layer, the method comprising:
- vapor-depositing the protective layer on the luminophore layer; and
 - hardening only a region of the protective layer that does not abut the luminophore layer.
18. (new) The method according to claim 17, wherein a region with a thickness of at least 5 μm that abuts the luminophore layer is not hardened.
19. (new) The method according to claim 17, wherein a region that does not abut the luminophore layer and that is hardened is at least 3 μm thick.
20. (new) The method according to claim 17, wherein the hardening ensues via electron beam treatment.
21. (new) The method according to claim 17, further comprising pre-treating the luminophore layer via a plasma treatment prior to the vapor-depositing of the protective layer.